

# ELECTRONIC INFORMATION DISCLOSURE STATEMENT

Electronic Version v18

Stylesheet Version v18.0

Title of  
Invention

[METHODS AND SYSTEMS FOR RESISTIVITY ANISOTROPY  
FORMATION ANALYSIS]

Application Number :

10/604492

Confirmation Number:

First Named Applicant:

Cheng Liu

Attorney Docket Number:

20.2807

Art Unit:

2863

Examiner:

V. TAYLOR

Search string:

( 5656930 or 6218841 or 5886526 or 6092024 or 5966013 or 5461562 or 5550473  
or 3166709 or 20020149997 or 20030018434 ).pn

## US Patent Documents

Note: Applicant is not required to submit a paper copy of cited US Patent Documents

init	Cite.No.	Patent No.	Date	Patentee	Kind	Class	Subclass
W	1	5656930	1997-08-12	Hagiwara		324	339
W	2	6218841*	2001-04-17	Wu		324	338
W	3	5886526*	1999-03-23	Wu		324	338
W	4	6092024*	2000-07-18	Wu		702	007
W	5	5966013 *	1999-10-12	Hagiwara		324	339
W	6	5461562 *	1995-10-24	Tabanou et al.		702	011
W	7	5550473*	1996-08-27	Klein		324	339
W	8	3166709	1959-04-17	Doll		324	339

## US Published Applications

Note: Applicant is not required to submit a paper copy of cited US Published Applications

init	Cite.No.	Pub. No.	Date	Applicant	Kind	Class	Subclass
W	1	20020149997	2002-10-17	Zhang et al.	A1	367	018
W	2	20030018434	2003-01-23	Kriegshauser et al.	A1	707	007

Signature

Examiner Name	Date
V. Taylor	3/31/2005

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ATTY. DOCKET NO.  
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(Use several sheets if necessary)

APPLICANT:  
Cheng Bing Liu et al.FILING DATE:  
07/25/2003GROUP  
N/A

## REFERENCE DESIGNATION U.S. PATENT DOCUMENTS

Examiner Initial	Document No.	Date	Patentee
AA			
AB			
AC			
AD			
AE			
AF			
AG			
AH			
AI			
AJ			
AK			
AL			

## FOREIGN PATENT DOCUMENTS

Document No.	Date	Country	Translation	
			Yes	No
AM				
AN				

## OTHER INFORMATION PROVIDED (AUTHOR, TITLE, DATE, PLACE OF PUBLICATION, PERTINENT PAGES, ETC.)

AO	Shray, Frank et al., Evaluation of Laminated Formations Using Nuclear Magnetic Resonance and Resistivity Anisotropy Measurements, SPE 72370, October 17-19, 2001, pp. 1-17.
AP	

EXAMINER

DATE CONSIDERED

EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to Applicant.

- The attached cited information should not be construed as an admission that any of the above items are prior art to the subject invention.
- This is not a representation that a search has been made.